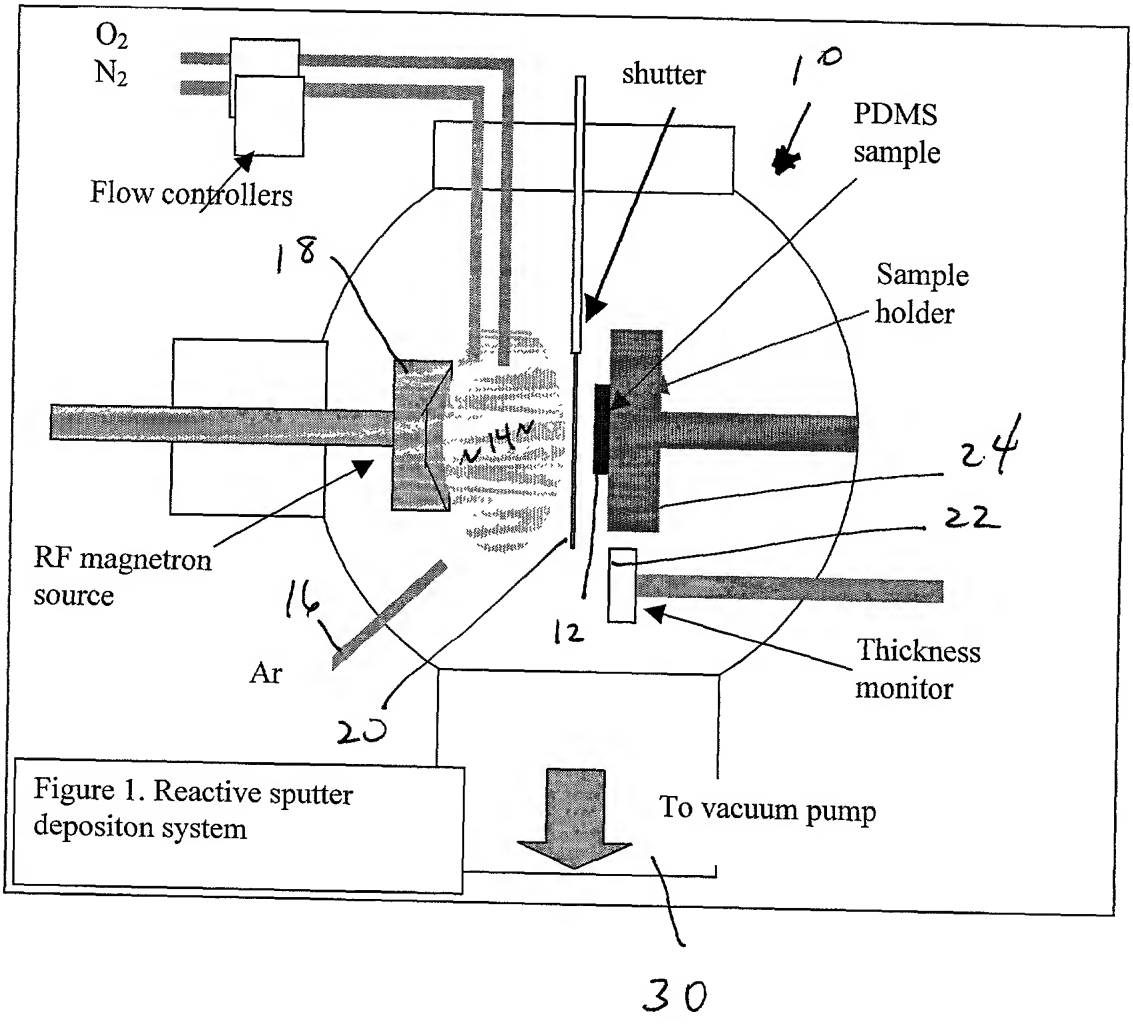

Figure 1. Reactive sputter depositon system

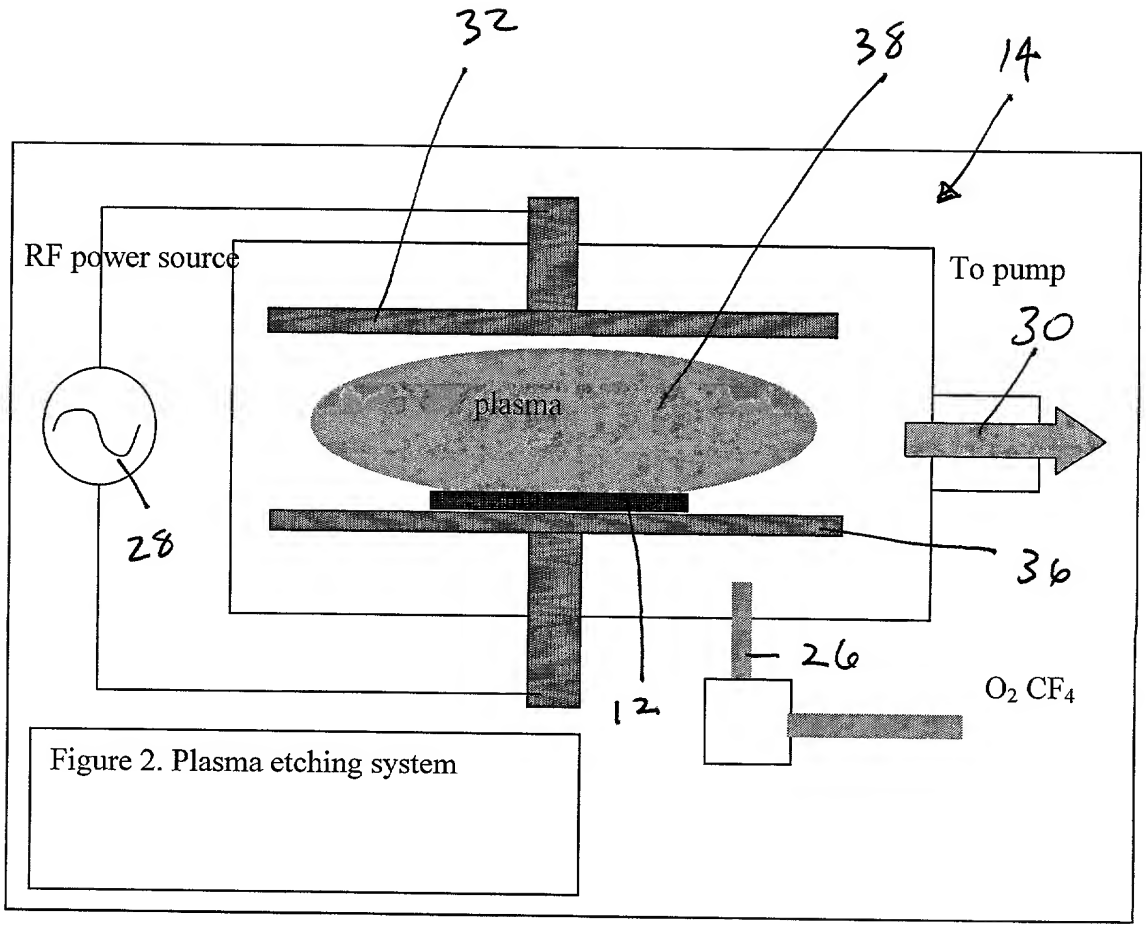

Figure 2. Plasma etching system